ULTRA Essential Specifications	
Resolution	1.0 nm @ 15 kV 1.7 nm @ 1 kV 4.0 nm @ 0.1 kV
Acceleration Voltage	0.1 - 30 kV
Probe Current	4 pA - 10 nA
Magnification	12 - 900,000x
Electron Emitter	Thermal Field Emission
Standard Detectors	SE In-lens, EsB In-column and ET chamber detector
Image Processing	7 integration and averaging modes
System Control	Windows®XP based SmartSEM™

ULTRA 55 FESEM

Nano-scale compositional imaging

SUPRA™55 VP Essential Specifications	
Resolution	1.0 nm @ 15 kV 1.7 nm @ 1 kV 4.0 nm @ 0.1 kV 2.0 nm @ 30 kV (VP mode)
VP Vacuum	2 - 133 Pa, adjustable in steps of 1 Pa
Magnification	12 - 900,000 x
Emitter	Thermal field emission type
Acceleration Voltage	0.1 - 30 kV
Probe Current	4 pA - 10 nA (20 nA optional)
Standard Detectors	High efficiency In-lens detector Everhart-Thornley Secondary Electron Detector VPSE Detector
Chamber	330 mm (Ø) x 270 mm (h) 1 EDS port 35° TOA CCD-camera with IR illumination
5-Axes Motorised Eucentric Specimen Stage	X = 130 mm Y = 130 mm Z = 50 mm T = -3 - 70° R = 360° (continuous)
Image Processing	Resolution: Up to 3072 x 2304 pixel Noise reduction: Seven integration and averaging modes
Image Display	Single flicker-free 19" XVGA monitor with SEM image displayed at 1024 x 768 pixel TFT optionally available
Image Hardcopy	Choice of Windows® driven laser, inkjet or video print media
System Control	SmartSEM™* with Windows®XP, operated by mouse, keyboard and joystick with optional control panel
SmartSEM™ – Fifth generation SEM control Graphical User Interface*	

VP 55